



520.34403CV4

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. MASUDA, et al
Serial No.: 09/421,043
Filed: October 20, 1999
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD
Group: 1763
Examiner: A. Mulero

AMENDMENT

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Mail Stop
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action August 13, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.